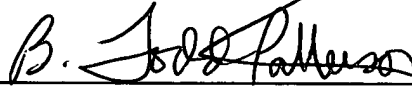


The patents and/or publications submitted herewith are set forth on the attached Form PTO-1449.

If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/8539/BTP.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "B. Todd Patterson", is written over a horizontal line.

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Attorney for Applicant(s)

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. APPM/8539		Serial No. Unassigned	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant Kim, et al.		Confirmation No. Unknown	
(Use several sheets if necessary)					Filing Date		Group	
Examiner Unknown					Herewith		Unknown	
U.S. Patent Documents								
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
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	B1	1 150 345	10/31/2001	EP	H01L	21/316	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B2	2001-189312	05/02/2001	JP	C30B	25/02	<input checked="" type="checkbox"/>	<input type="checkbox"/>
	B3	63062313	03/18/1988	JP (abstract)	H01L	21/203	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B4	58098917	06/13/1983	JP	H01L	21/205	<input type="checkbox"/>	<input checked="" type="checkbox"/>
OTHER ART								
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	C1	Lee, et al., <i>Cyclic technique for the enhancement of highly oriented diamond film growth</i> , Elsevier Science S.A., Thin Solid Films (1997) 264-268.						
	C2	Choi, et al., <i>Stability of TiB₂ as a Diffusion Barrier on Silicon</i> . Electrochemical Society Vol. 138 No. 10 October 1991.						
Examiner					Date Considered			
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(Use several sheets if necessary)					Filing Date		Group	
Examiner Unknown					Herewith		Unknown	
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*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
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	B6	2001-189312	07/10/2001	JP	H01L	21/316	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B7	2001-111000	04/20/2001	JP	H01L	27/105	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B8	5102189	04/23/1993	JP	H01L	21/336	<input type="checkbox"/>	<input checked="" type="checkbox"/>
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	C3	Paranjpe, et al., <i>Atomic Layer Deposition of AlO_x for Thin Film Head Gap Applications</i> , ECS, Journal of the Electrochemical Society, 148 (9) G465-G471 (2001).						
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Examiner Unknown					Herewith		Unknown	
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	A30	2001/0046567	11/29/2001	Matsuki, et al.	427	578	04/06/2001	
	A31	2001/0024871	09/27/2001	Yagi	438	604	01/31/2001	
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Foreign Patent Documents								
*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
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	B7	2001-111000	04/20/2001	JP	H01L	27/105	<input type="checkbox"/>	<input checked="" type="checkbox"/>
OTHER ART								
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
	C3							
	C4							
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